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| Substitute for Form 1449A/PTO | | | | Complete if Known | |
| INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i> | | | | Application Number | Based on SN 10/035,441 |
| | | | | Filing Date | Filed: January 4, 2002 |
| | | | | First Named Inventor | Naoaki YAMAGUCH et al. |
| | | | | Group Art Unit | 1765 |
| | | | | Examiner Name | Anita Karen Alanko |
| | | | | Attorney Docket Number | 0756-7191 |
| Sheet | 3 | of | 3 | | |

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| <p>Substitute for Form 1449A/PTO</p> <h2>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</h2> <p><i>(use as many sheets as necessary)</i></p> | | | | <p>Complete if Known</p> <table border="1"> <tr> <td>Application Number</td> <td>Based on SN 10/035,441</td> </tr> <tr> <td>Filing Date</td> <td>Filed: January 4, 2002</td> </tr> <tr> <td>First Named Inventor</td> <td>Naoaki YAMAGUCHI et al.</td> </tr> <tr> <td>Group Art Unit</td> <td>1765</td> </tr> <tr> <td>Examiner Name</td> <td>Anita Karen Alanko</td> </tr> <tr> <td>Sheet</td> <td>2</td> <td>of</td> <td>3</td> <td>Attorney Docket Number</td> <td>0756-7191</td> </tr> </table> | | Application Number | Based on SN 10/035,441 | Filing Date | Filed: January 4, 2002 | First Named Inventor | Naoaki YAMAGUCHI et al. | Group Art Unit | 1765 | Examiner Name | Anita Karen Alanko | Sheet | 2 | of | 3 | Attorney Docket Number | 0756-7191 |
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